

図1

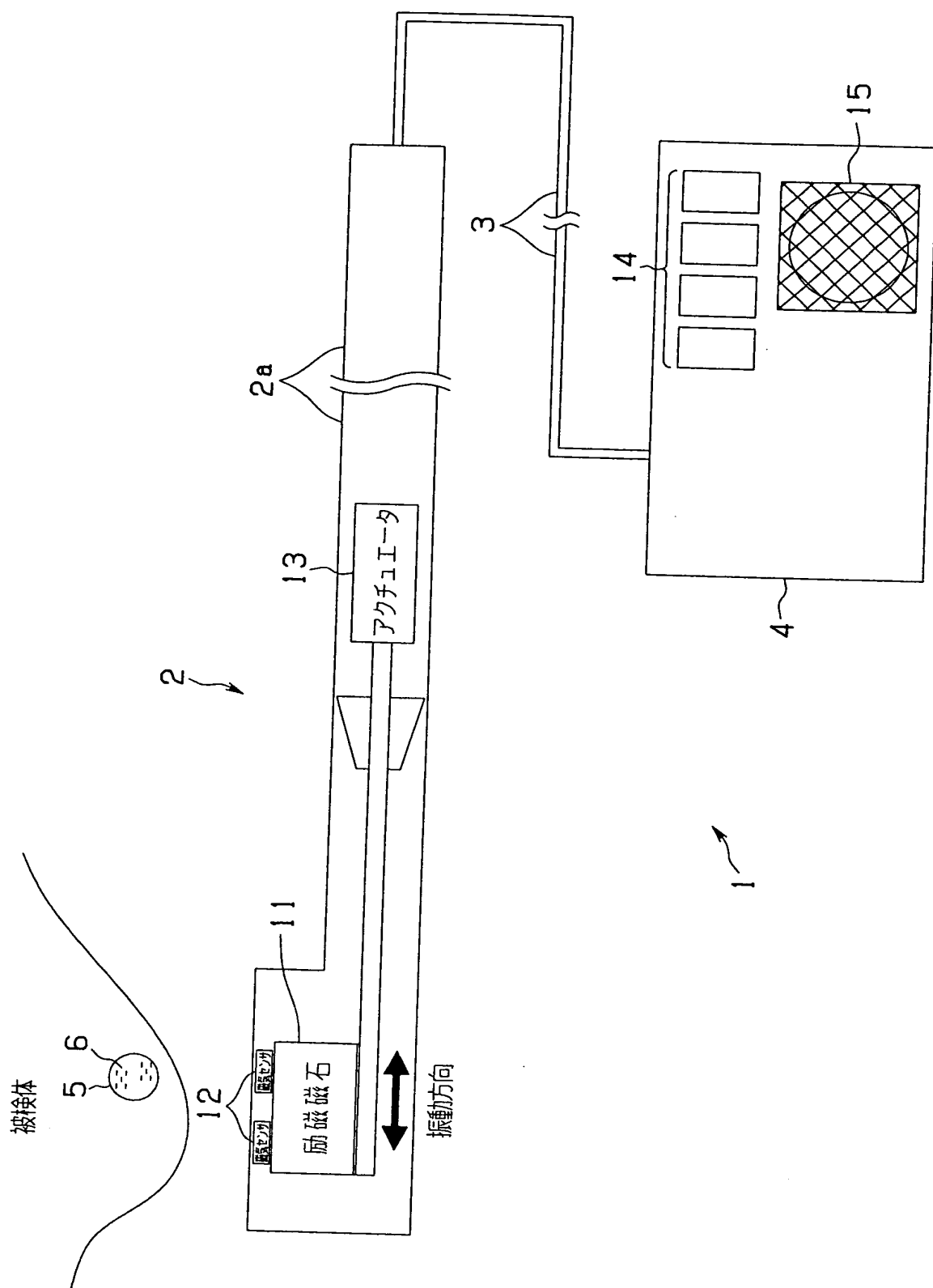


图2A

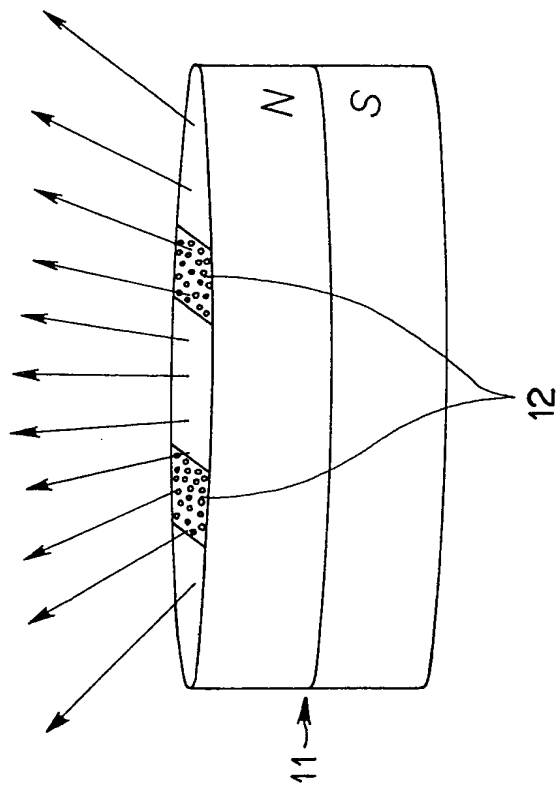


图2B

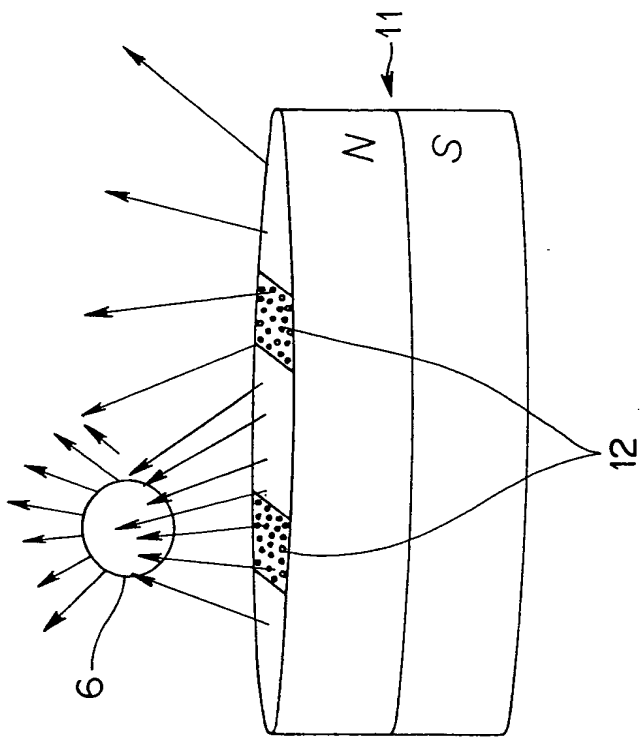


图3A

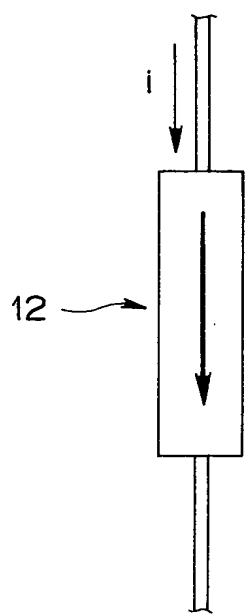


图3B

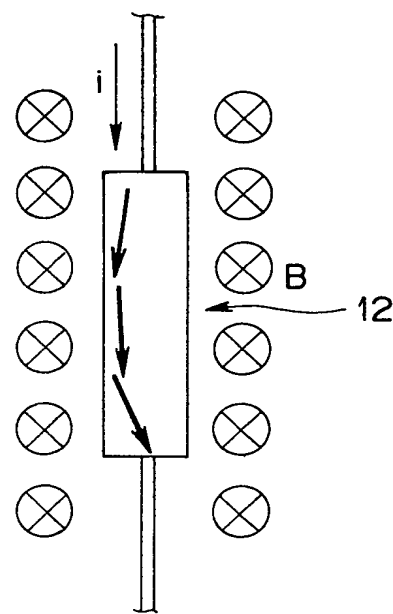


图4A

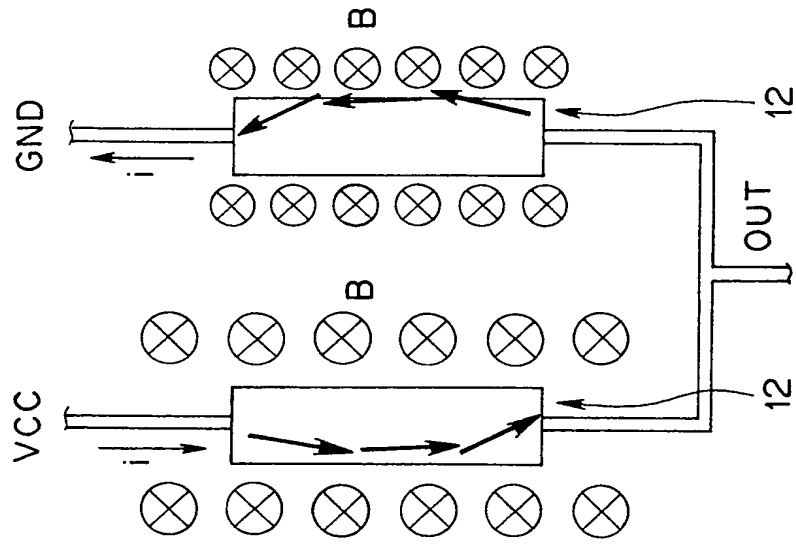


图4B

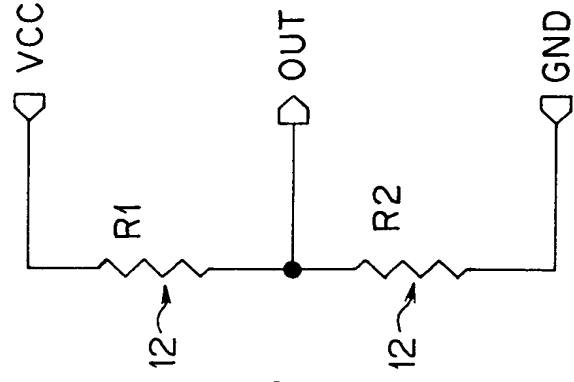
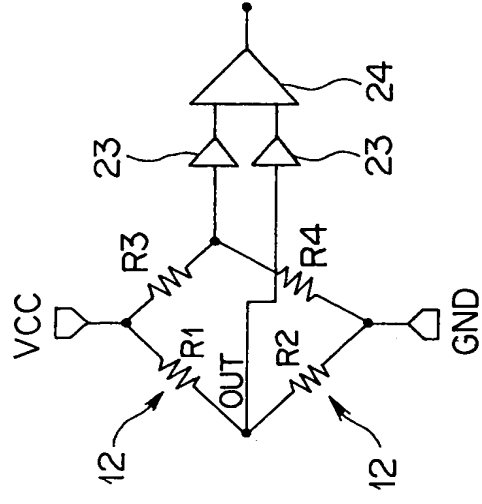


图4C



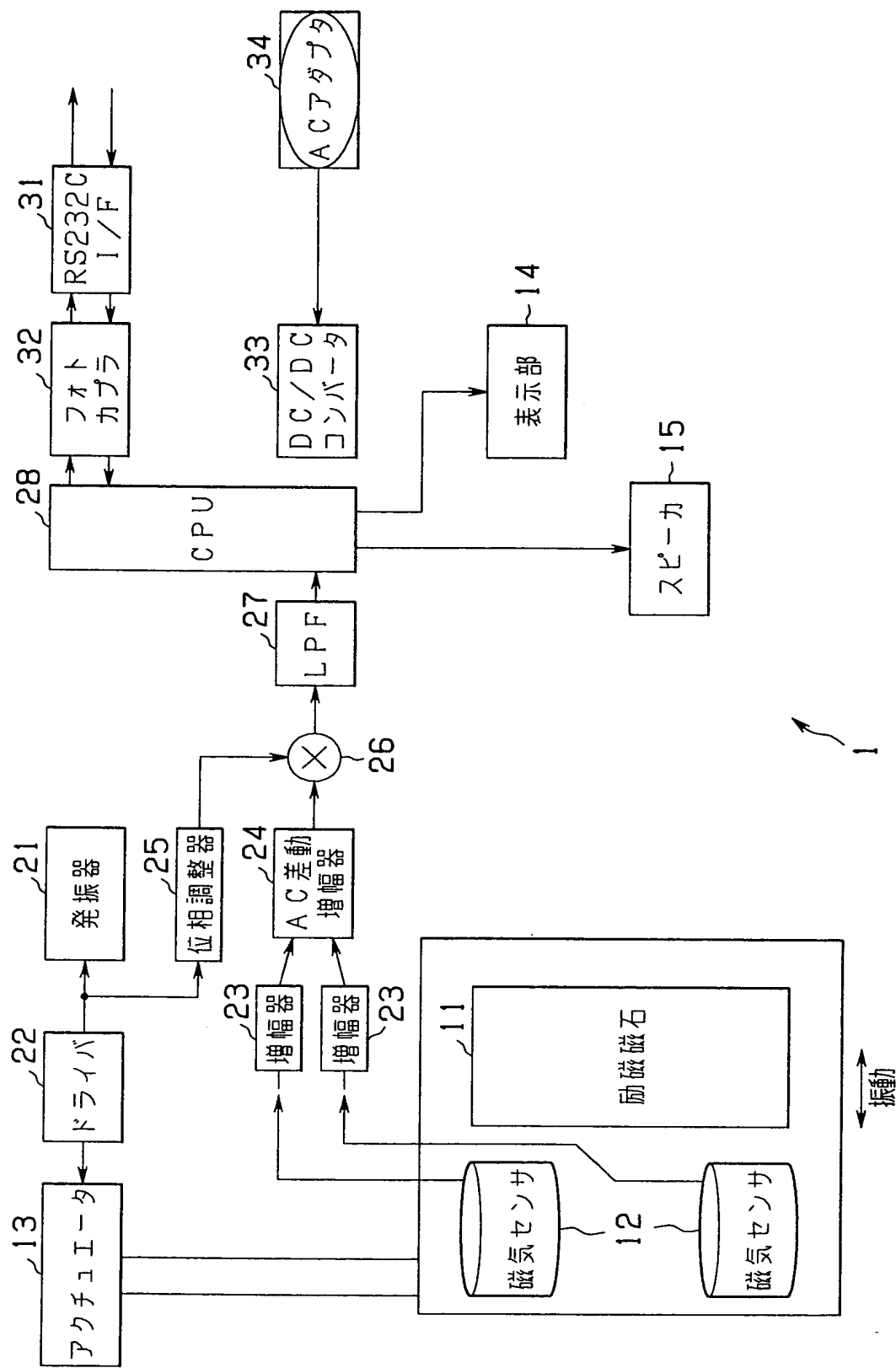


図 6

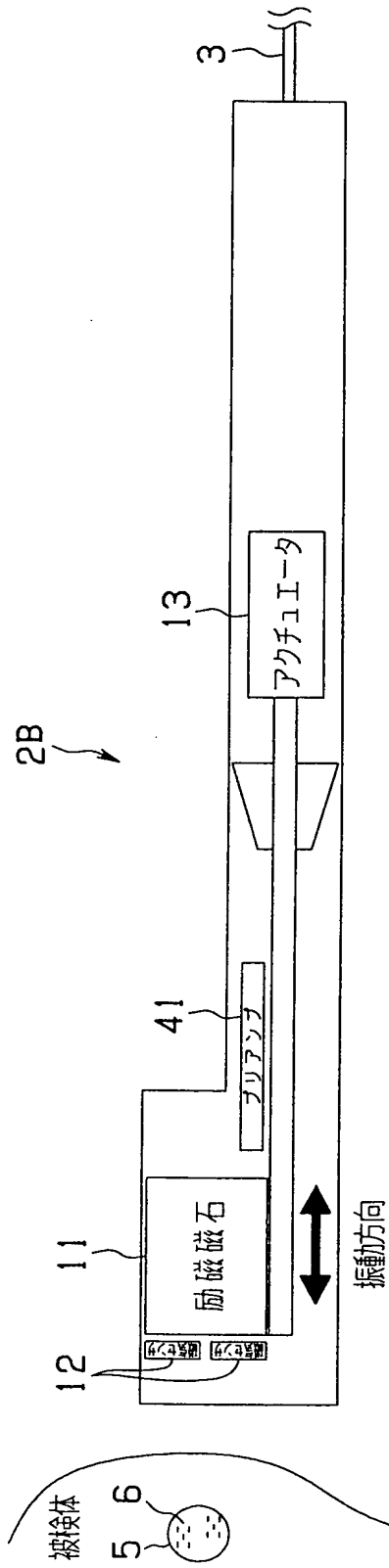


図 8

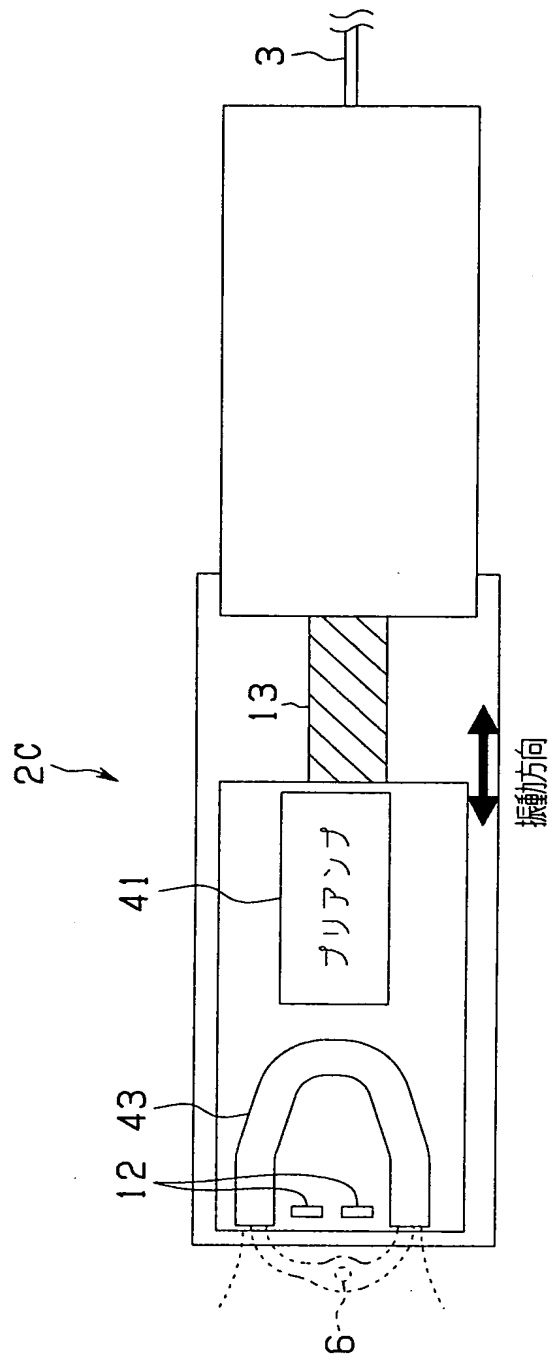


図 7

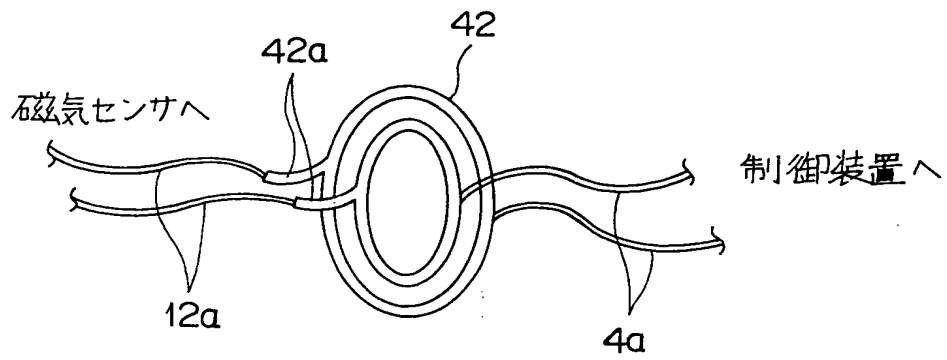


図 12

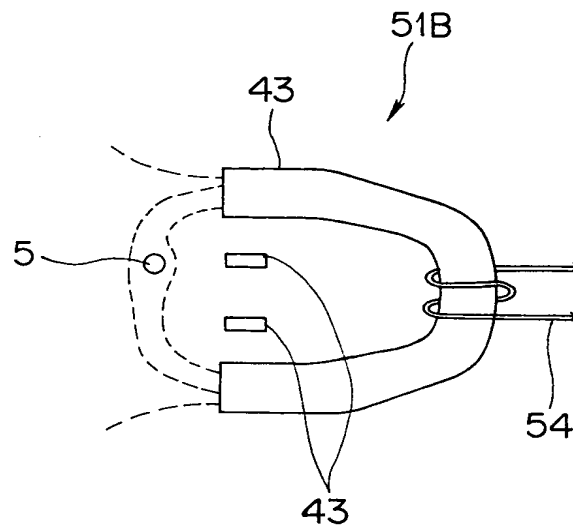


図 16A

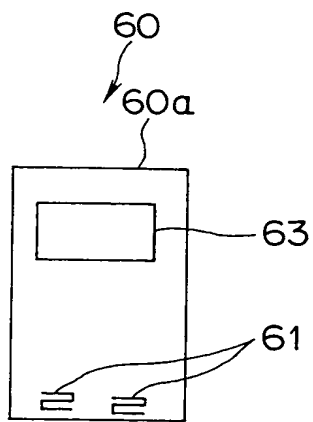
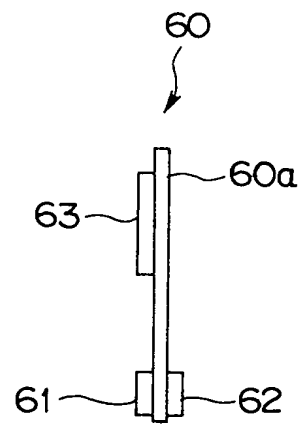
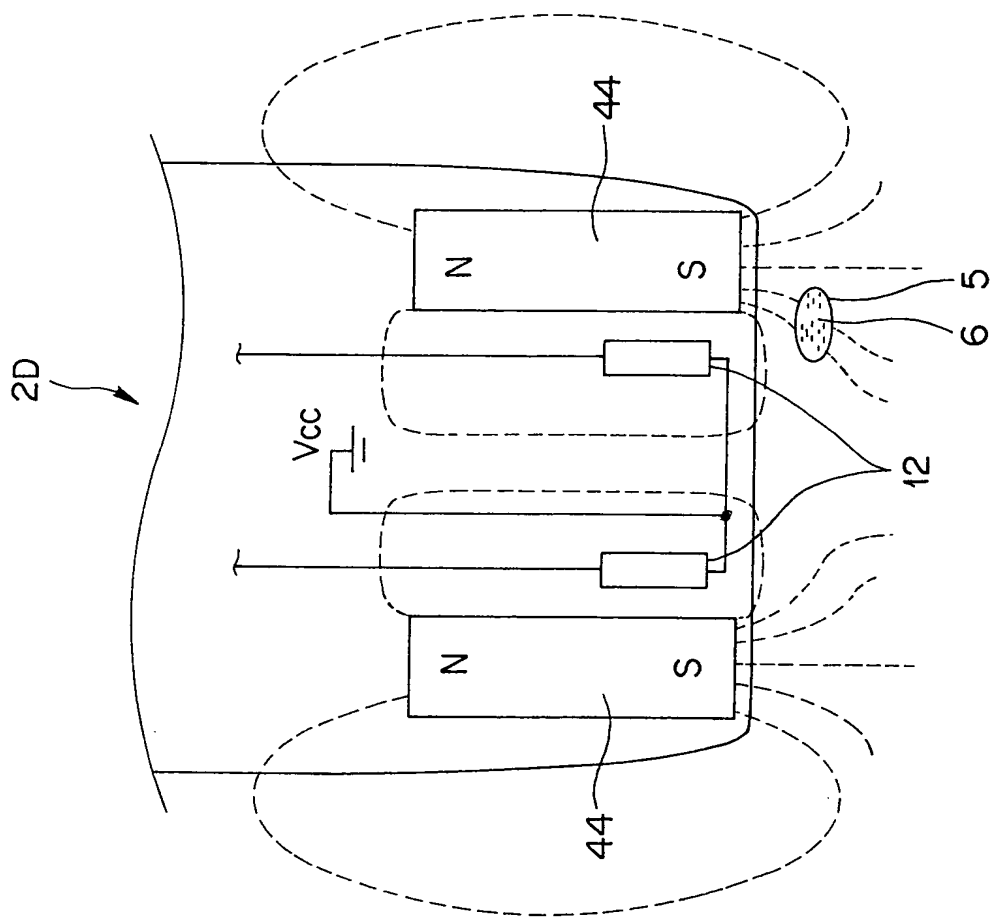


図 16 B







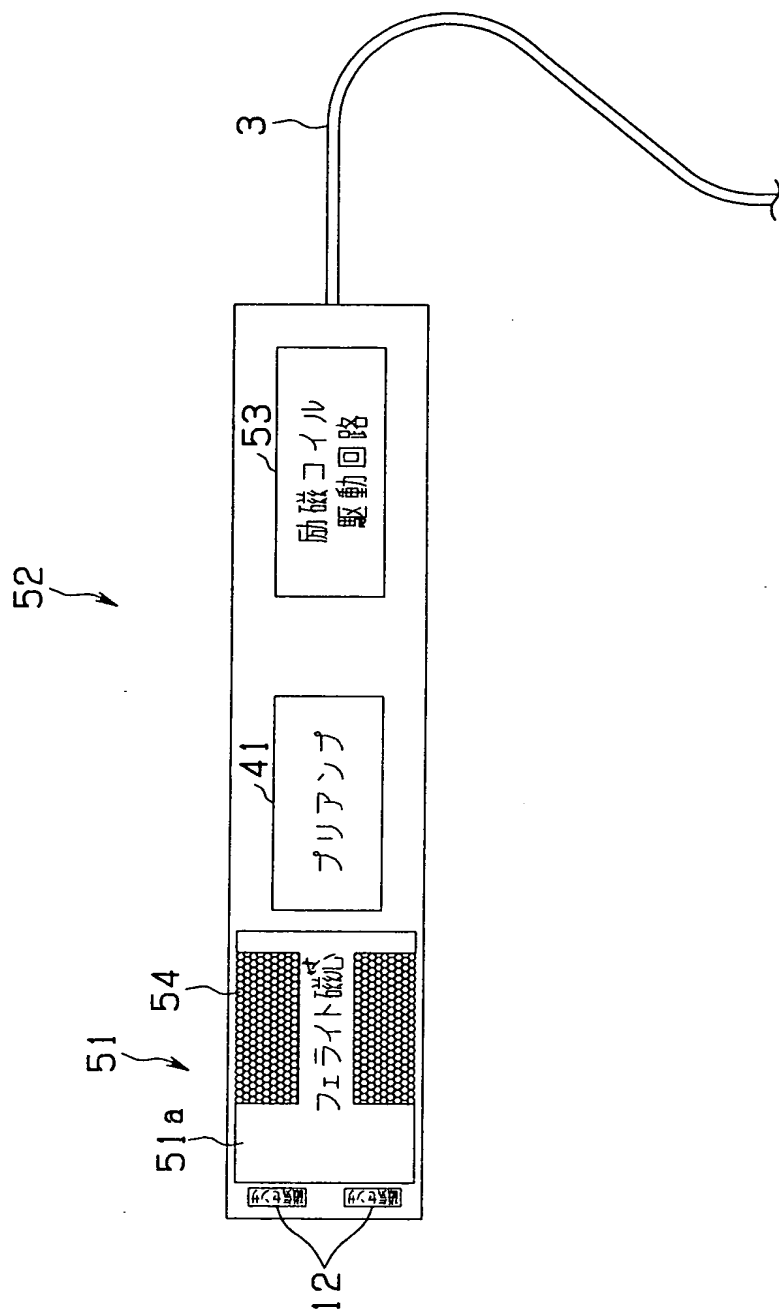
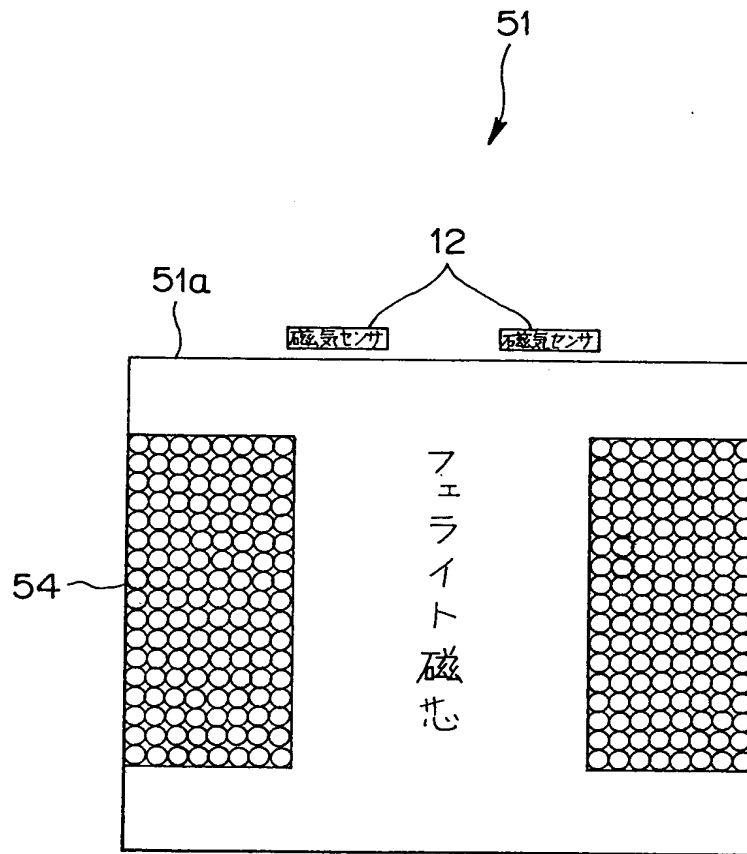


図 11



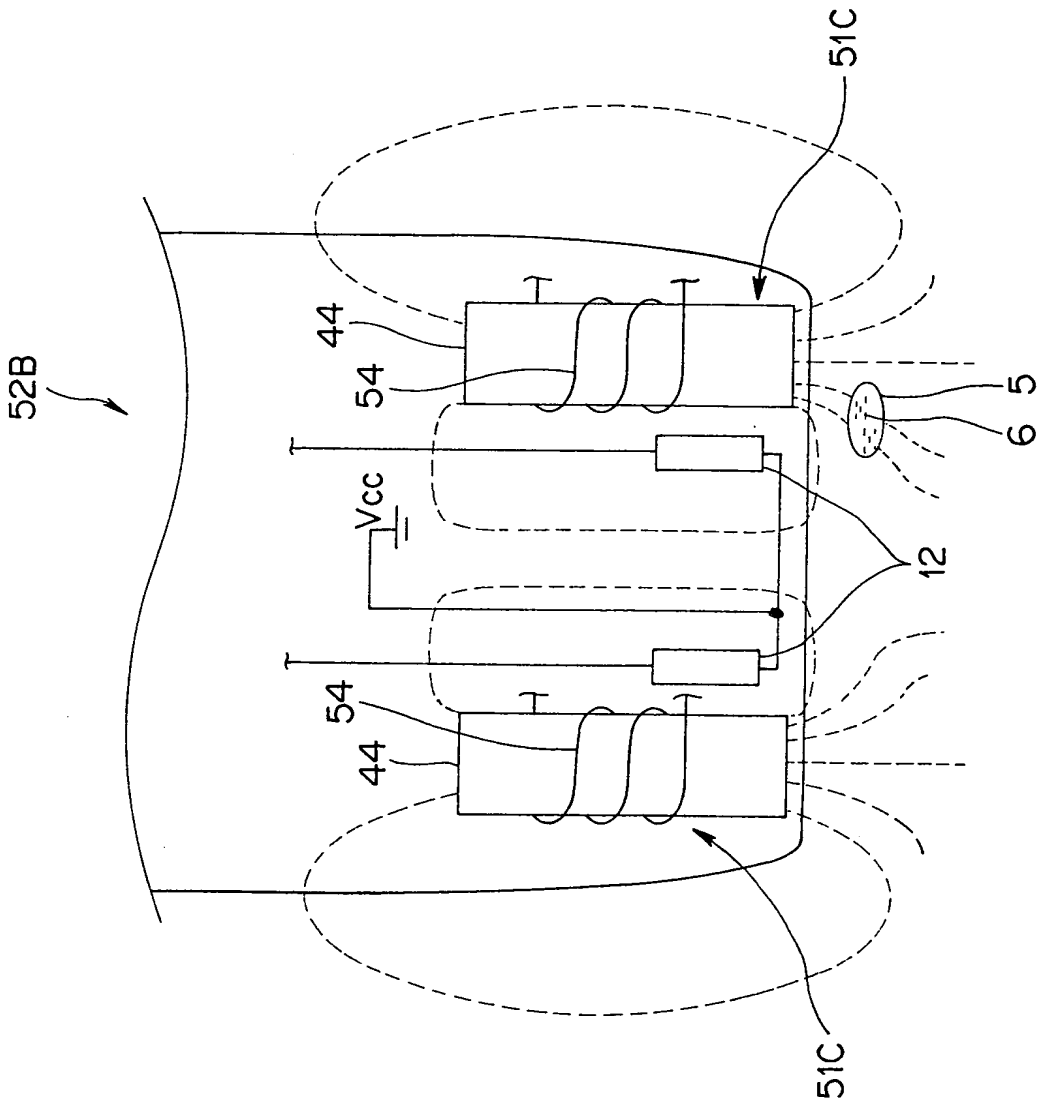


図14A

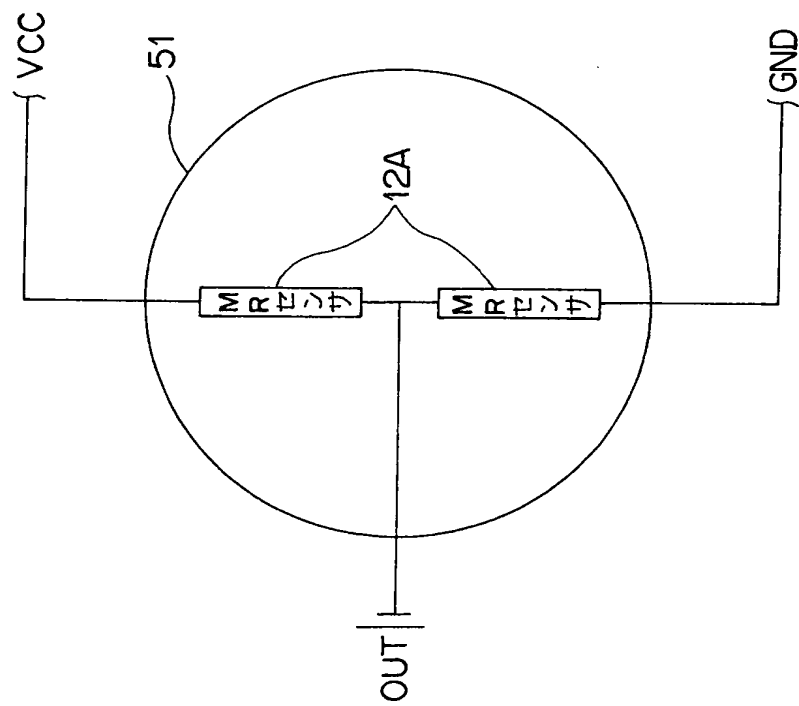


図14B

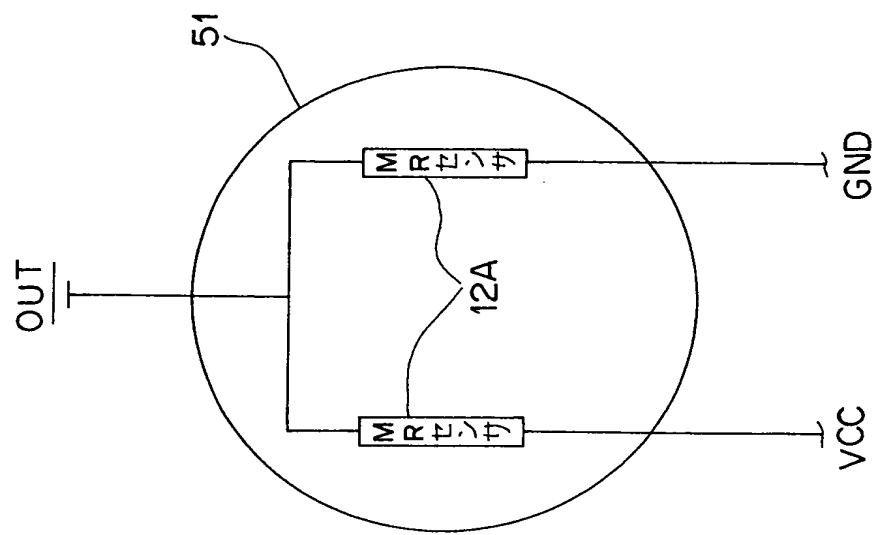


図15

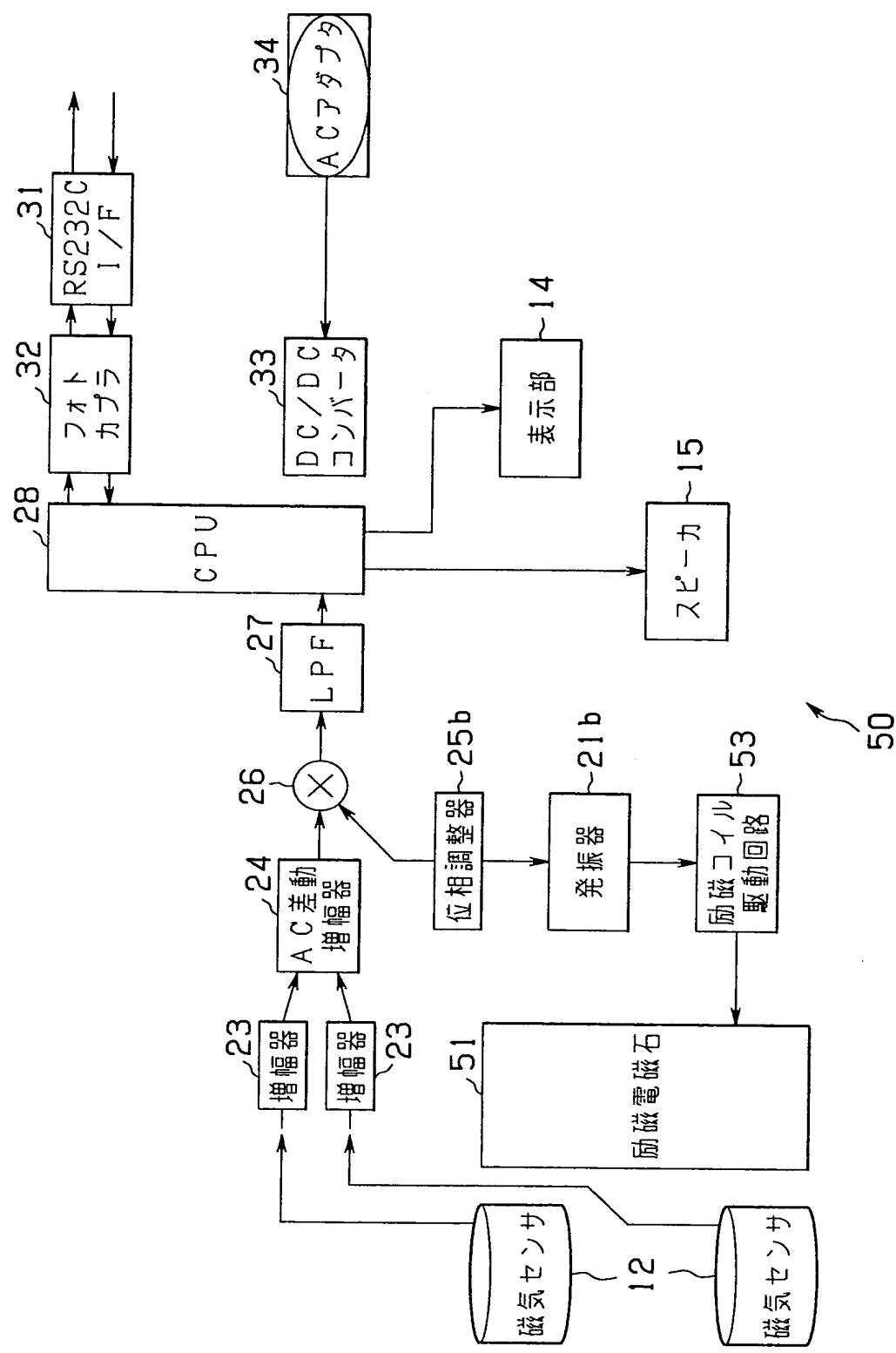


図17

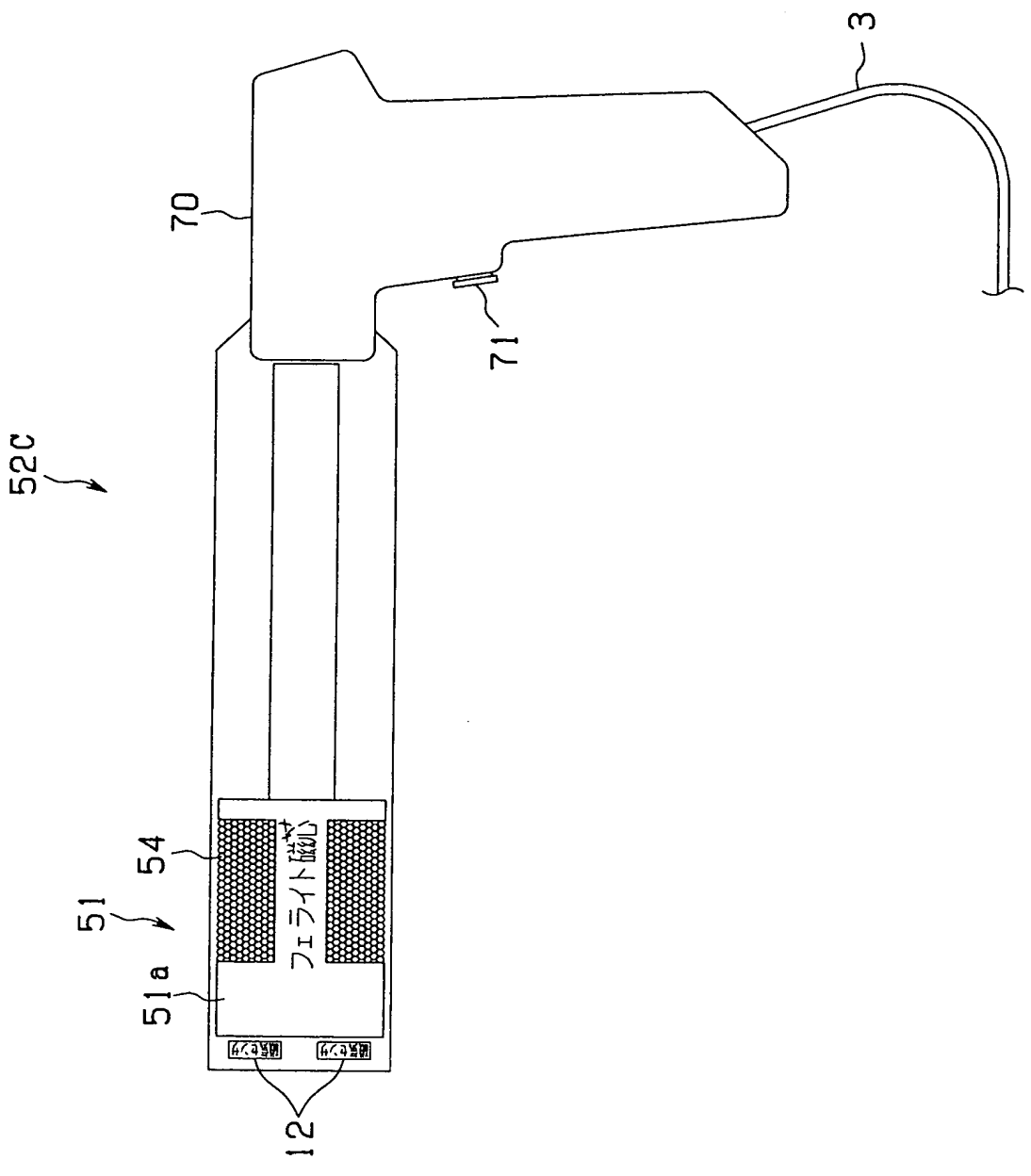


図18

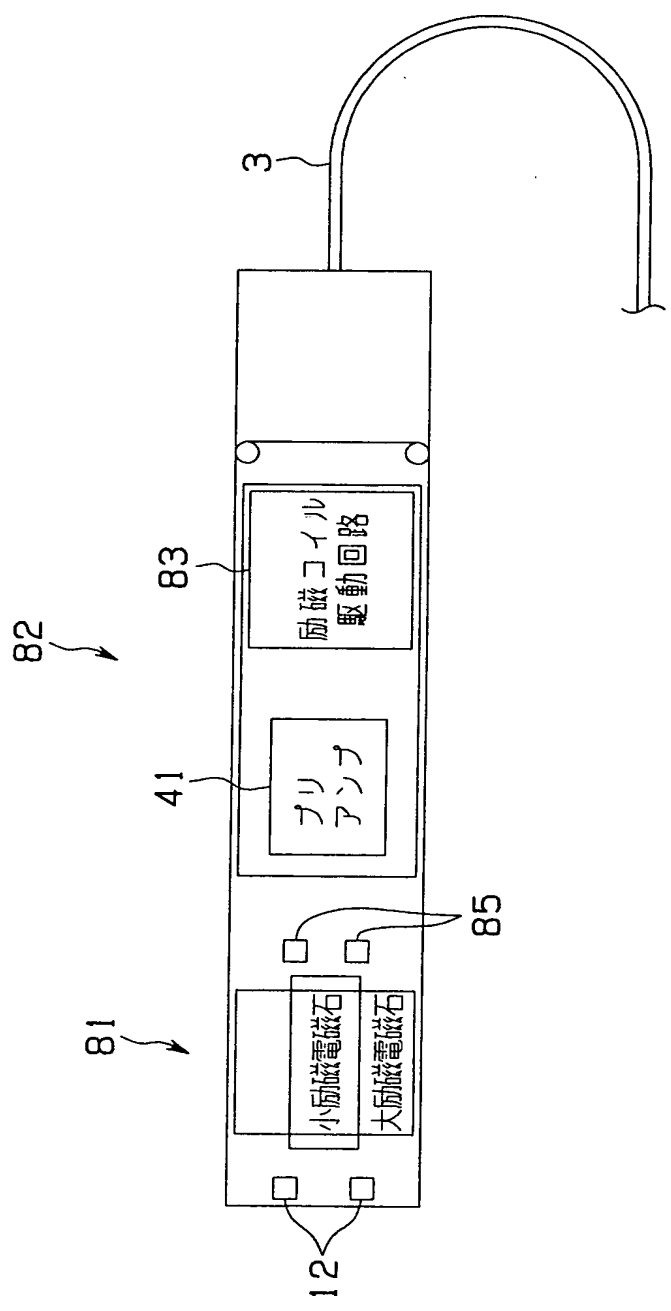


図 19

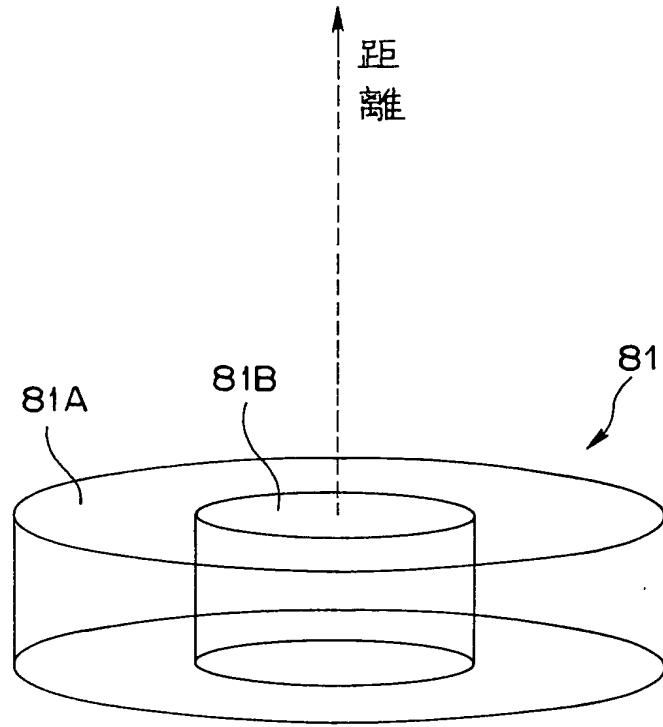
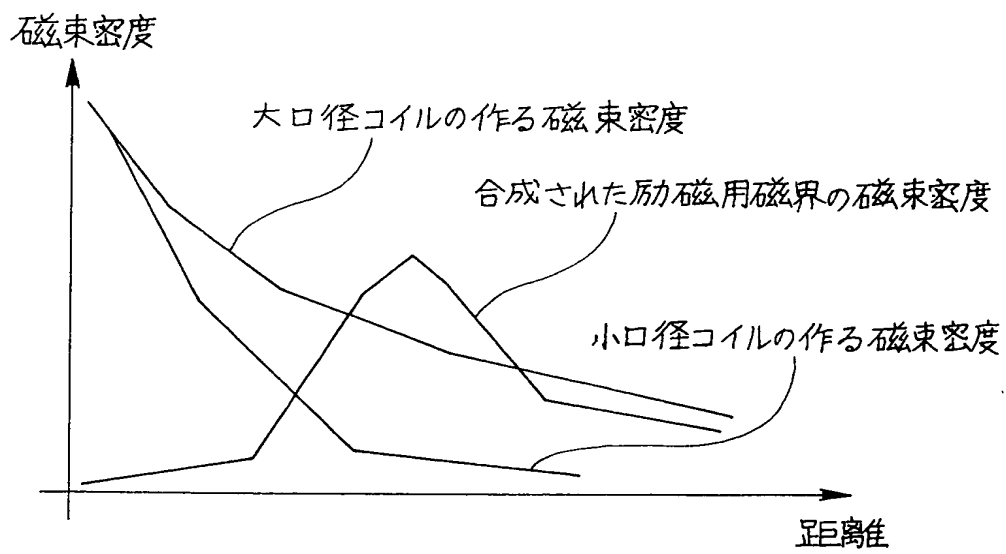


図 20





圖

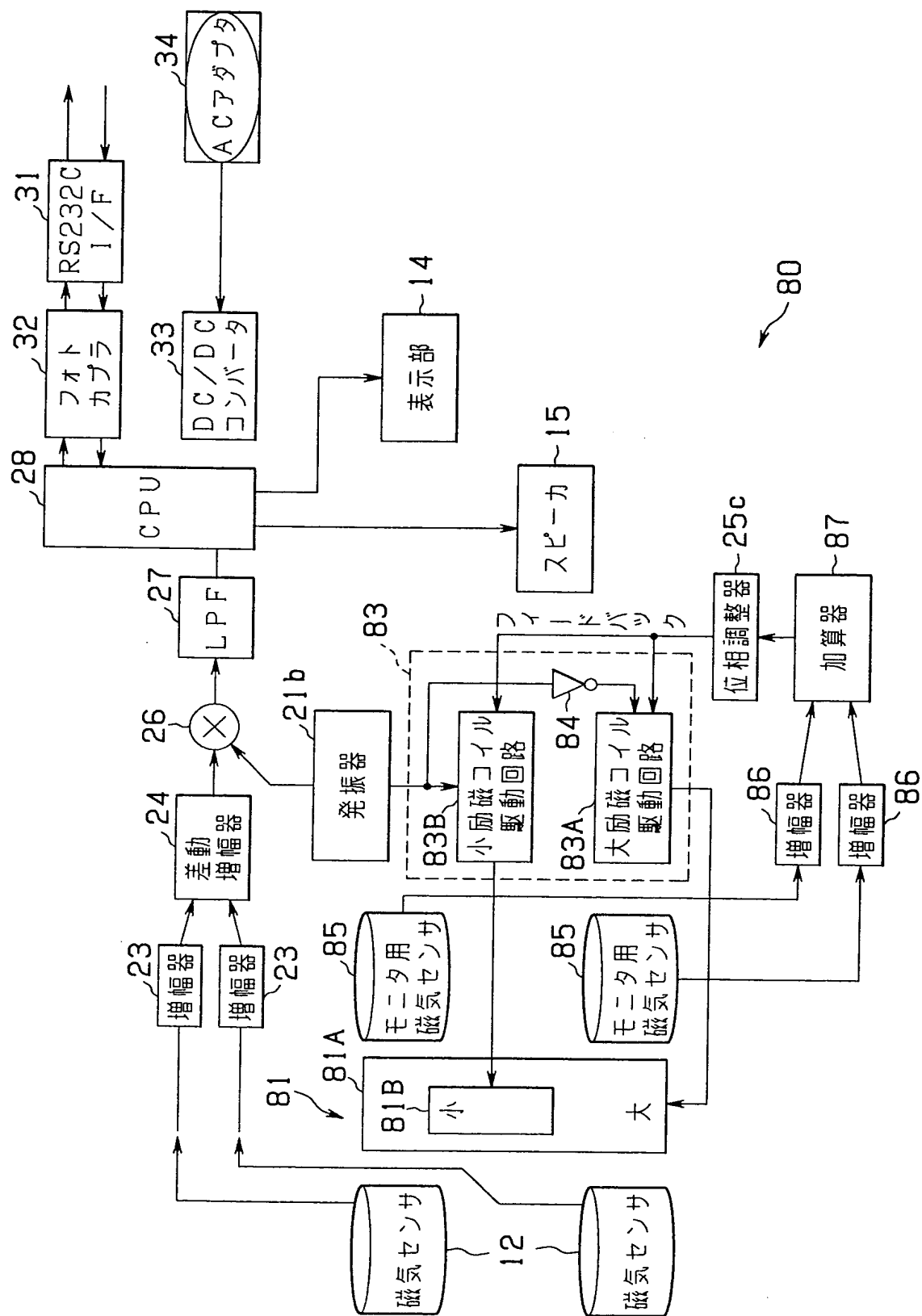
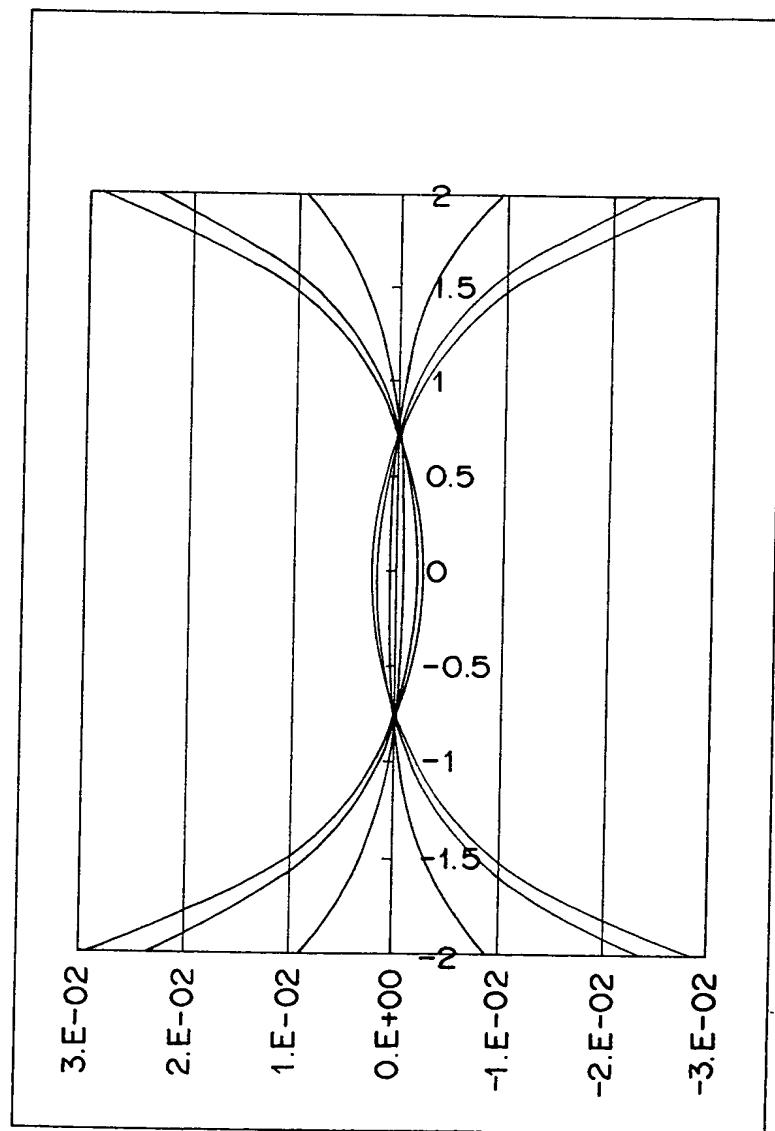


図22



X: センサ面位置 (mm)  
Y: 磁束密度 (T)  
時間変化による各位置での  
磁束密度変化

図23

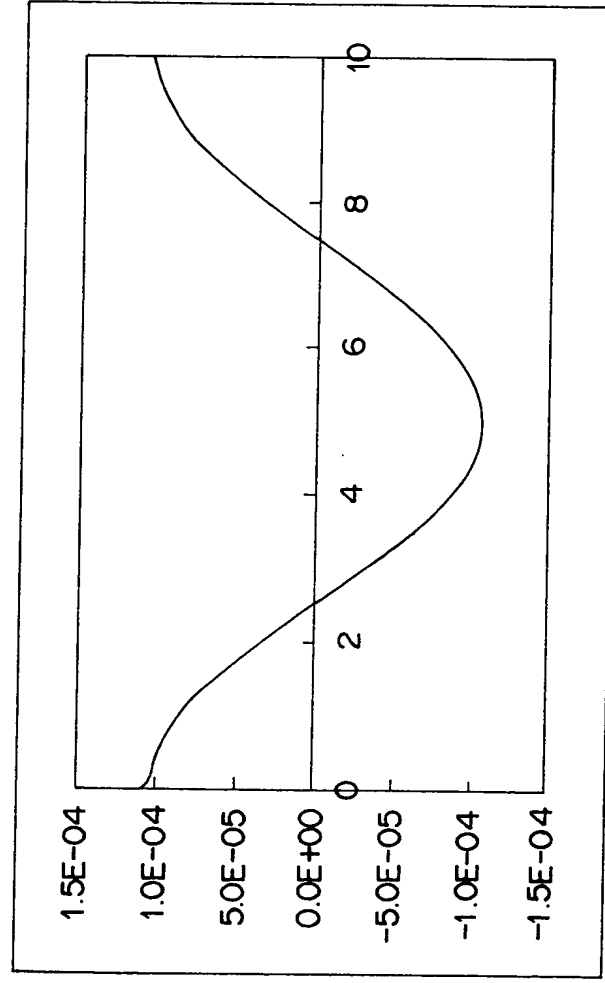


図24

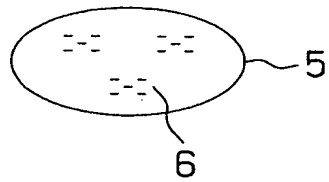
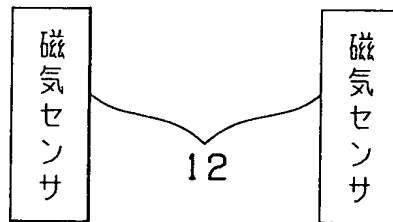
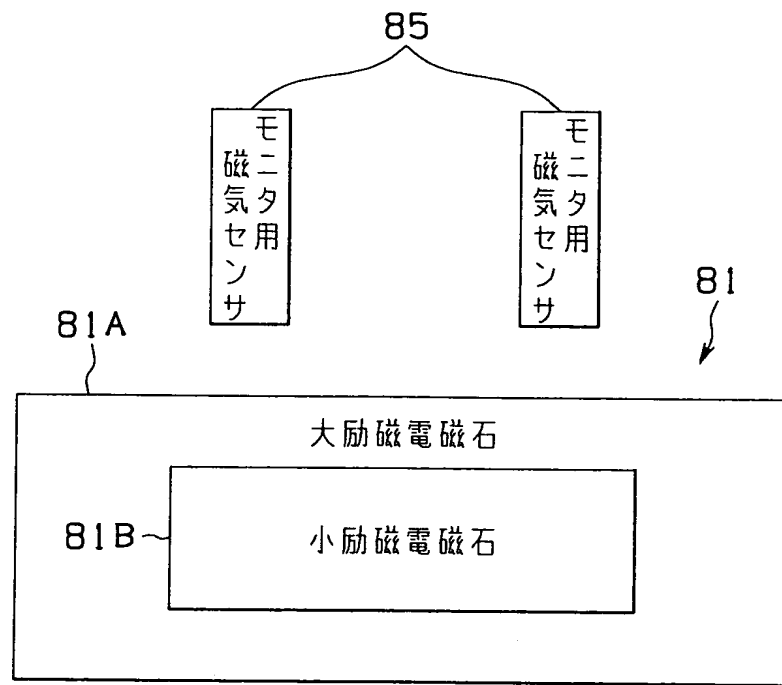


図25

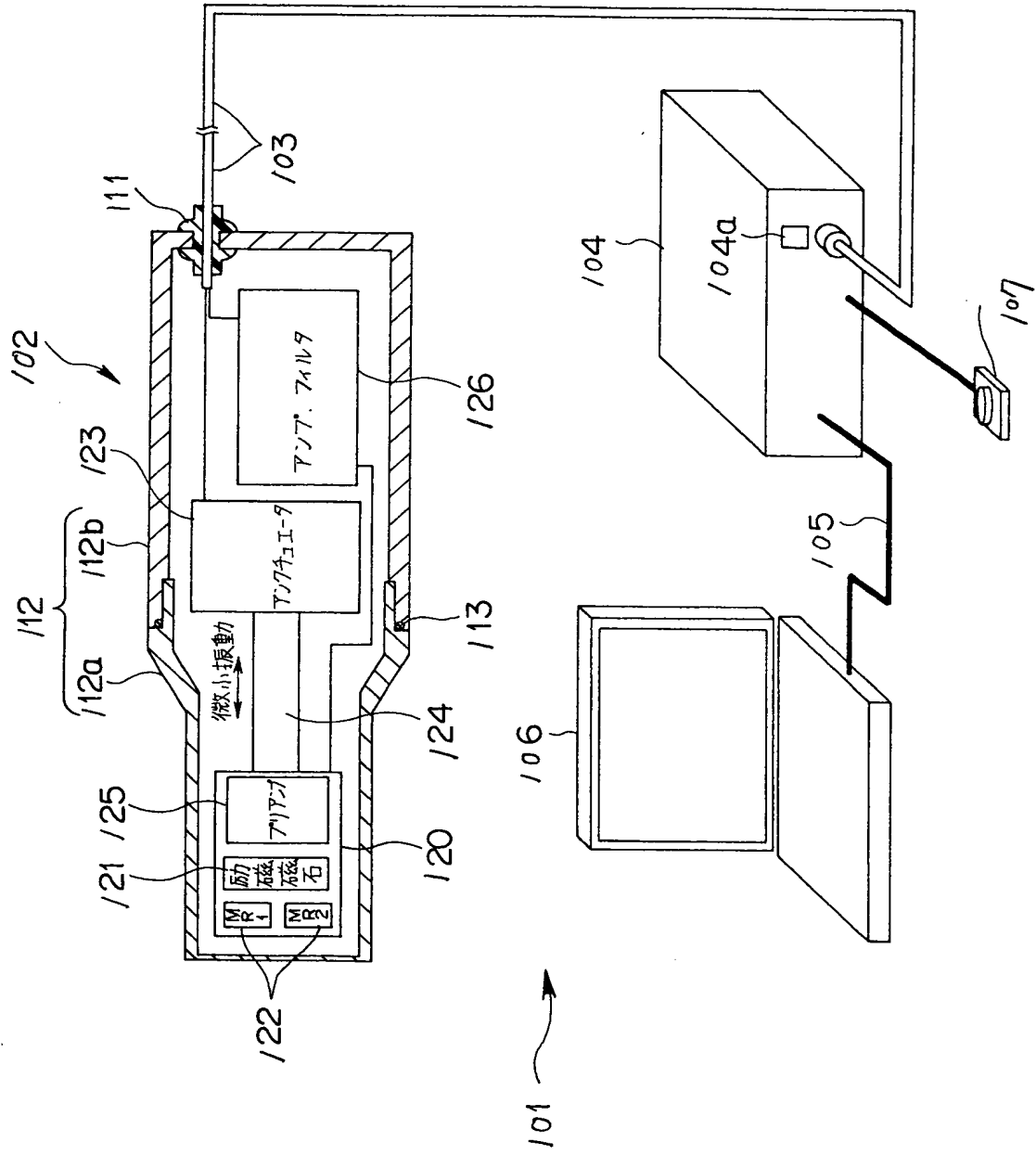


図26

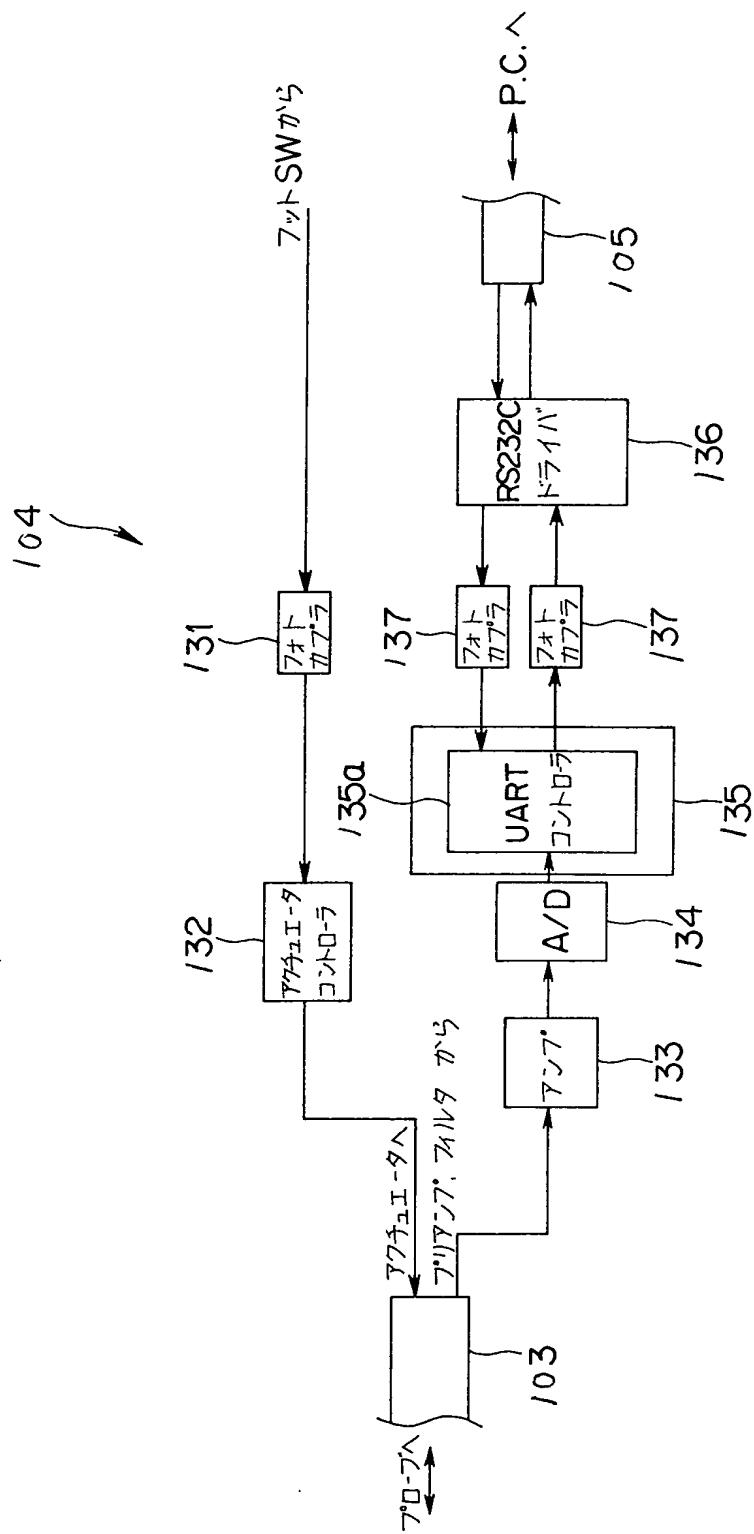


図27

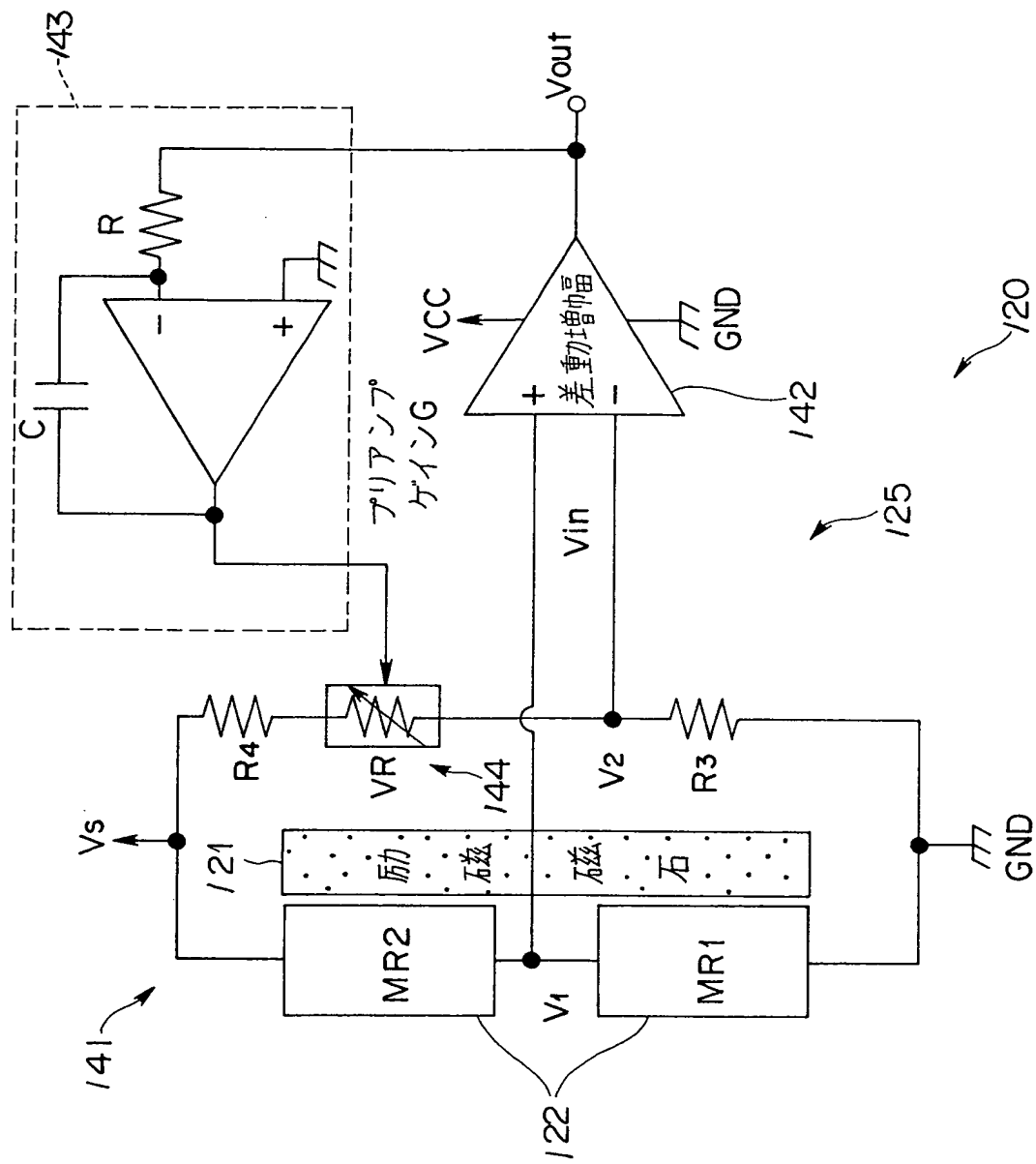


図28

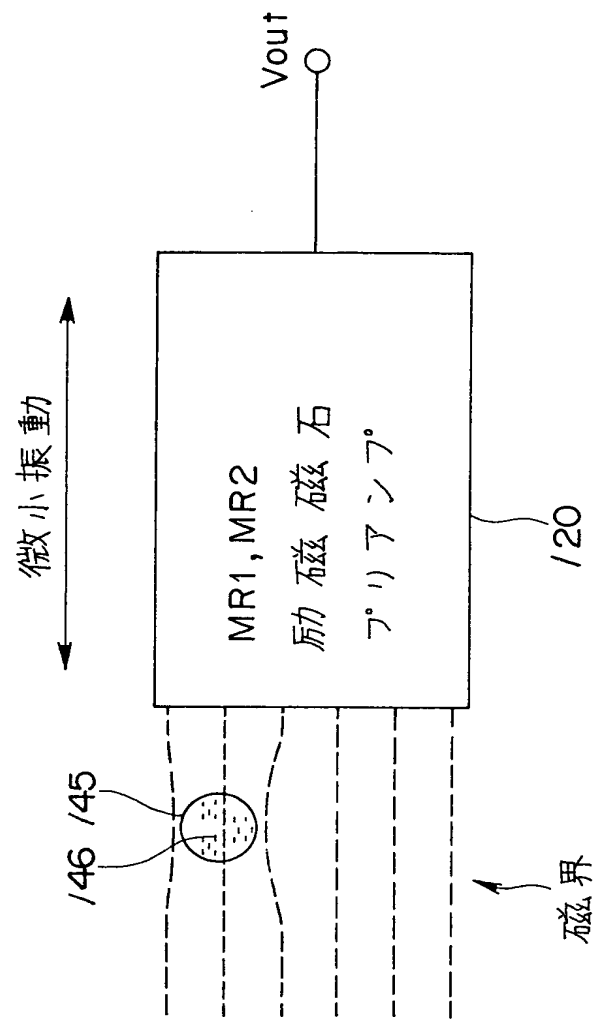




図29

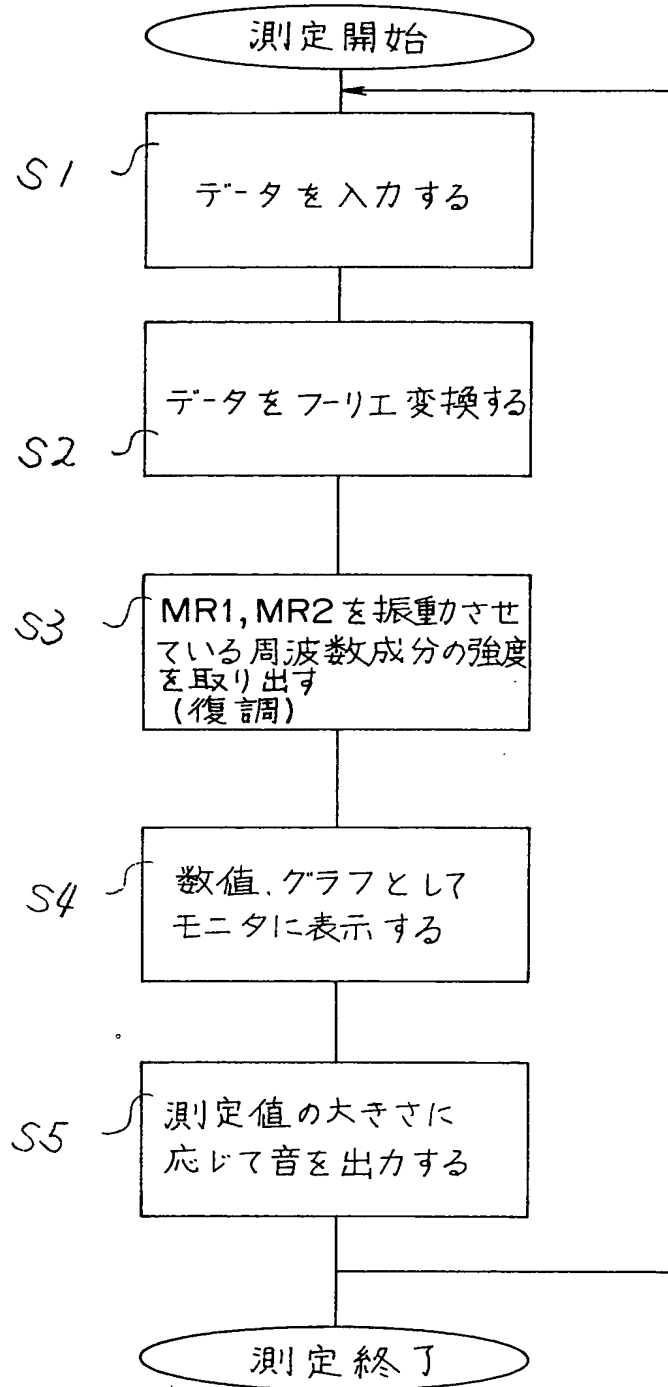


图 30

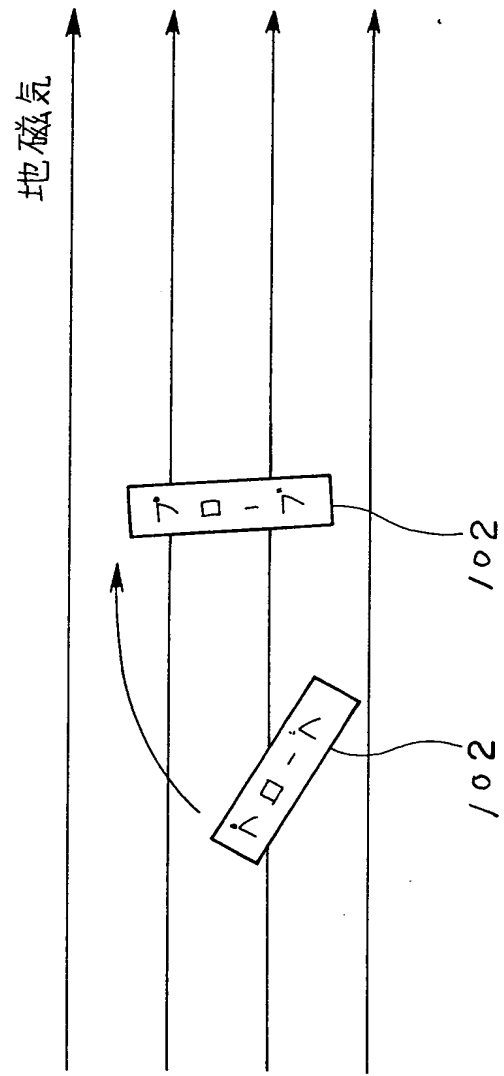


図31

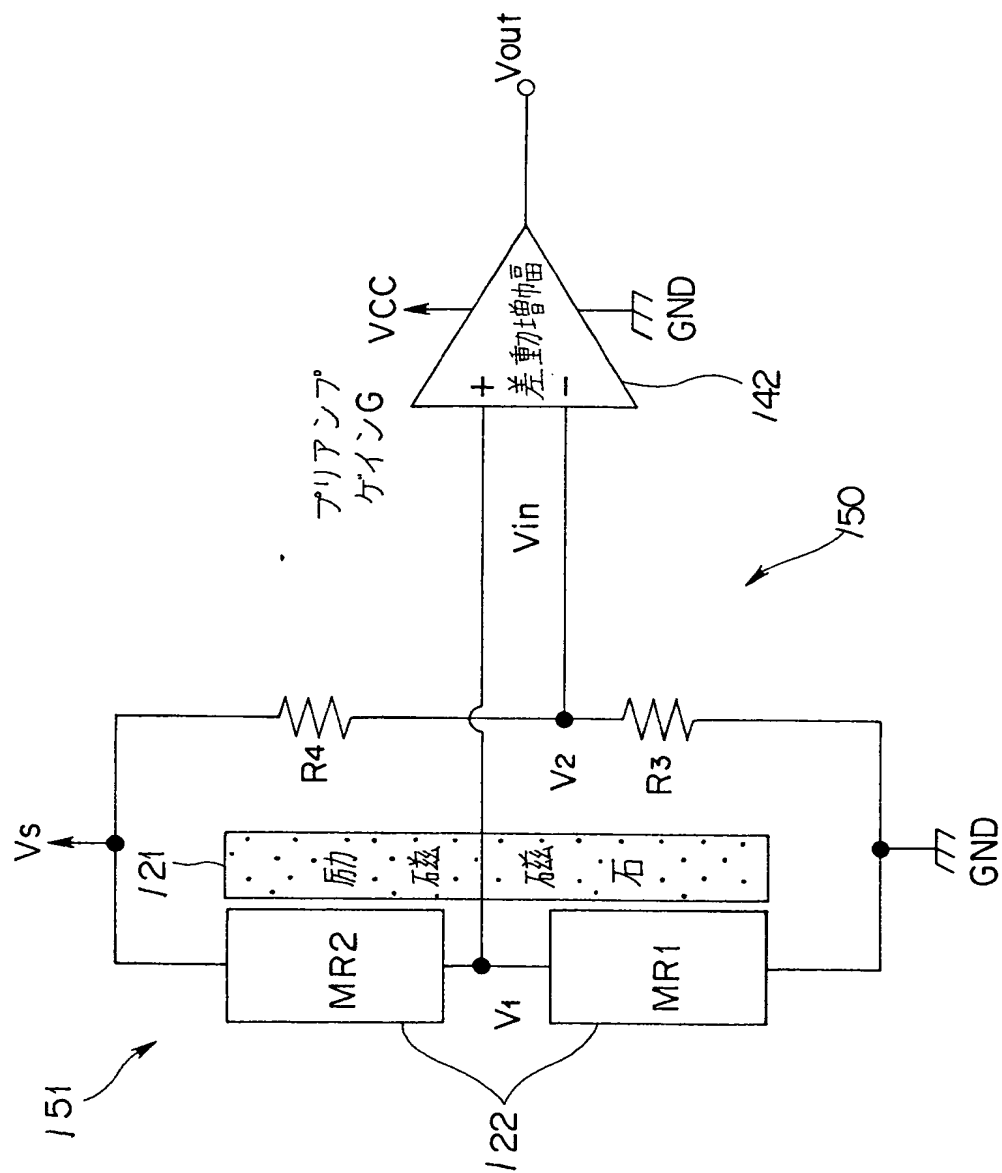


图32

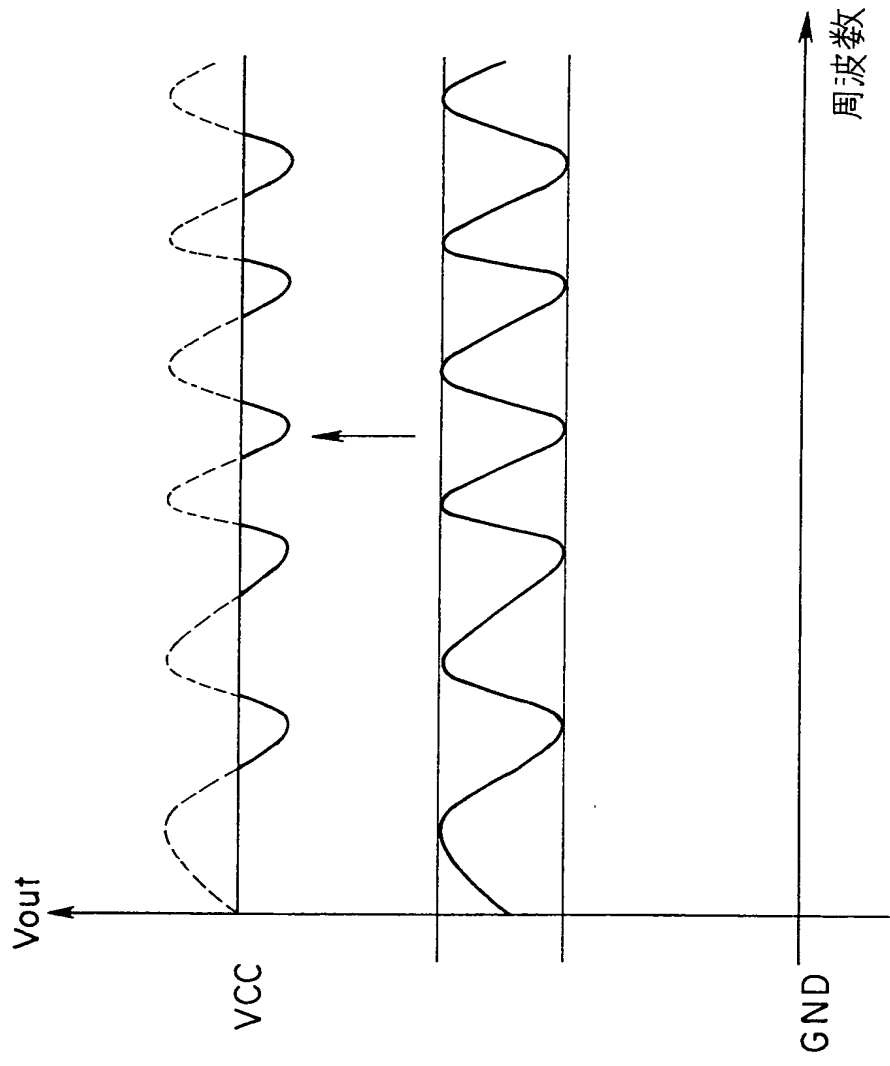


図33

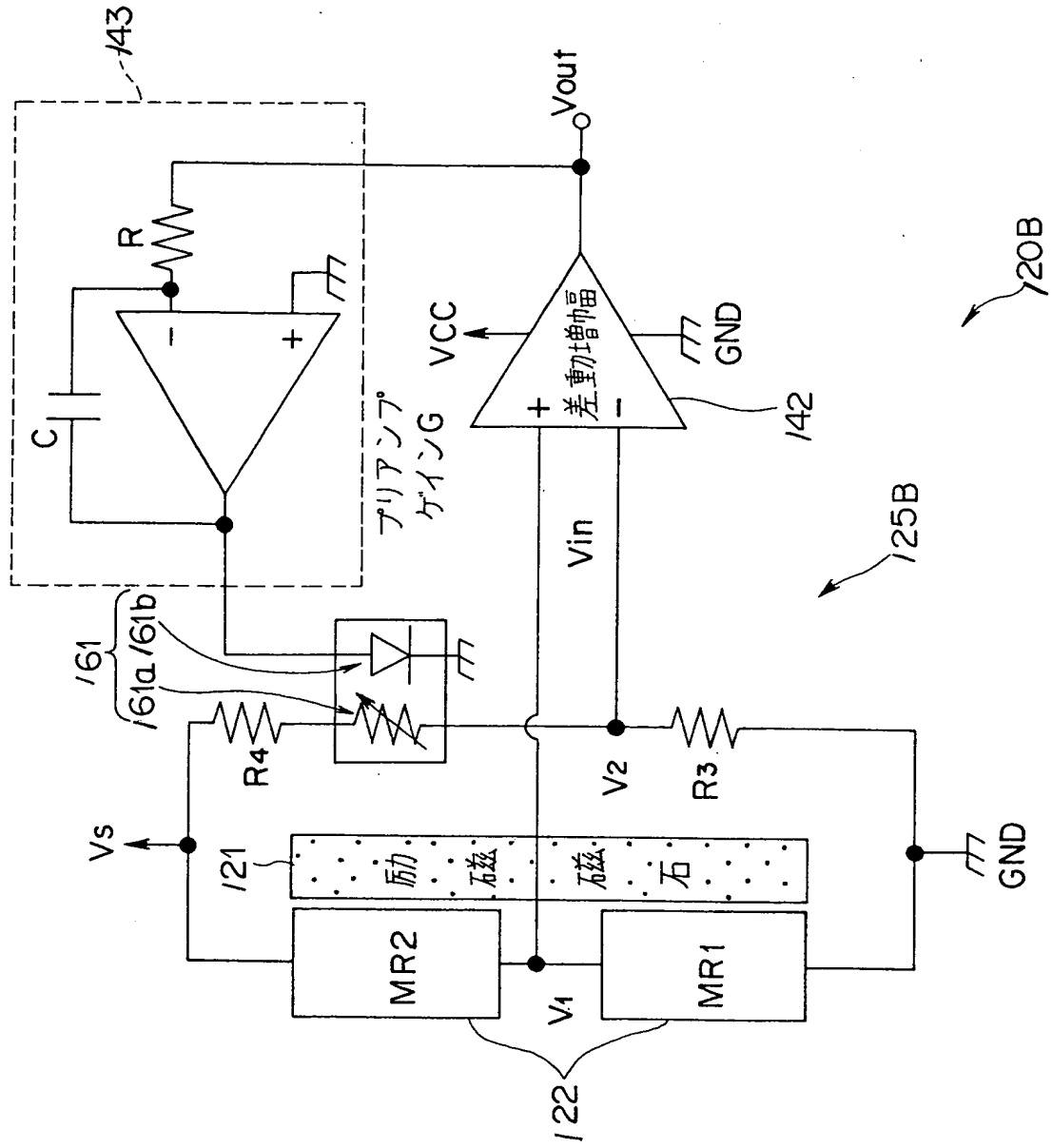


図34

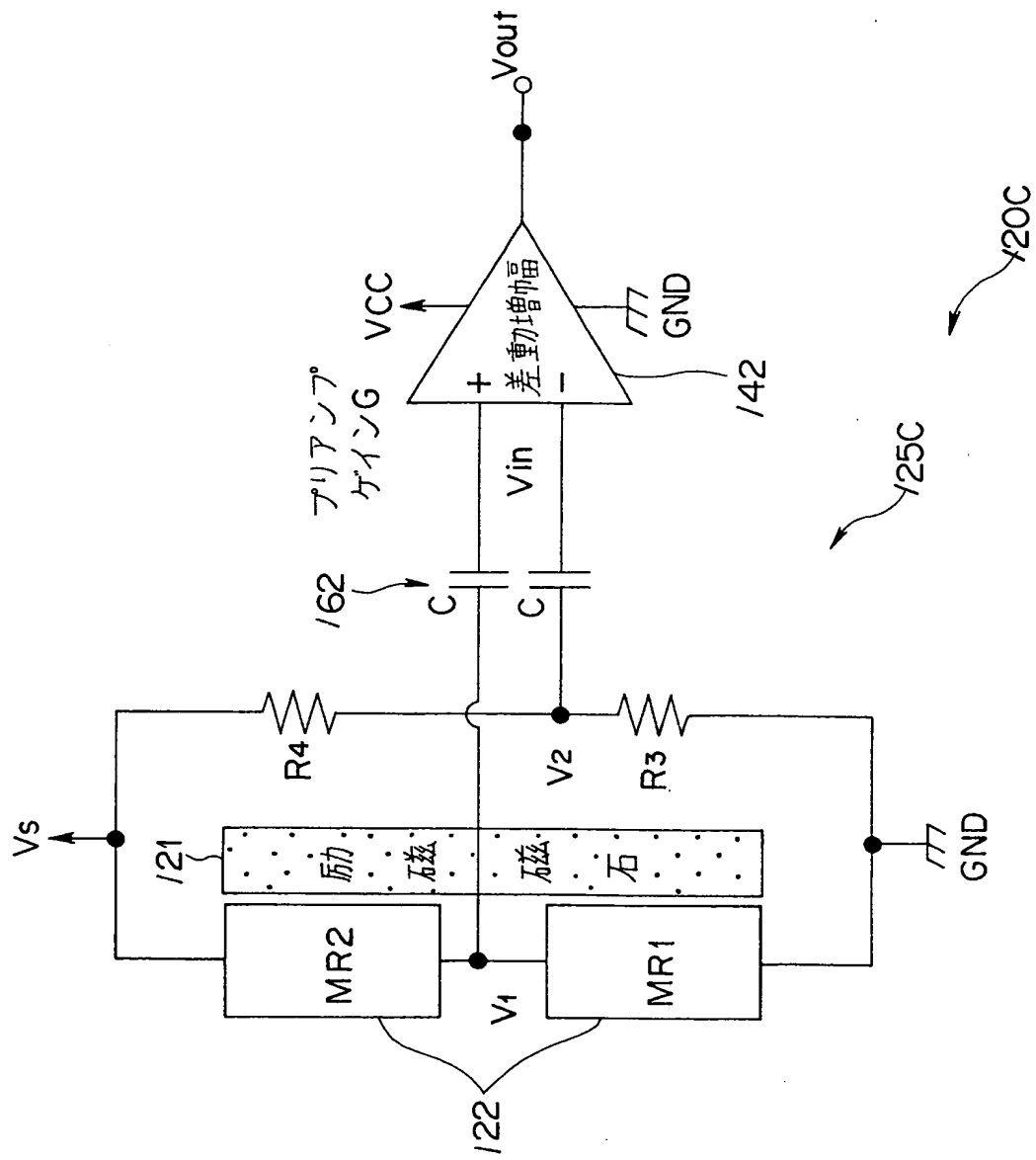


図35

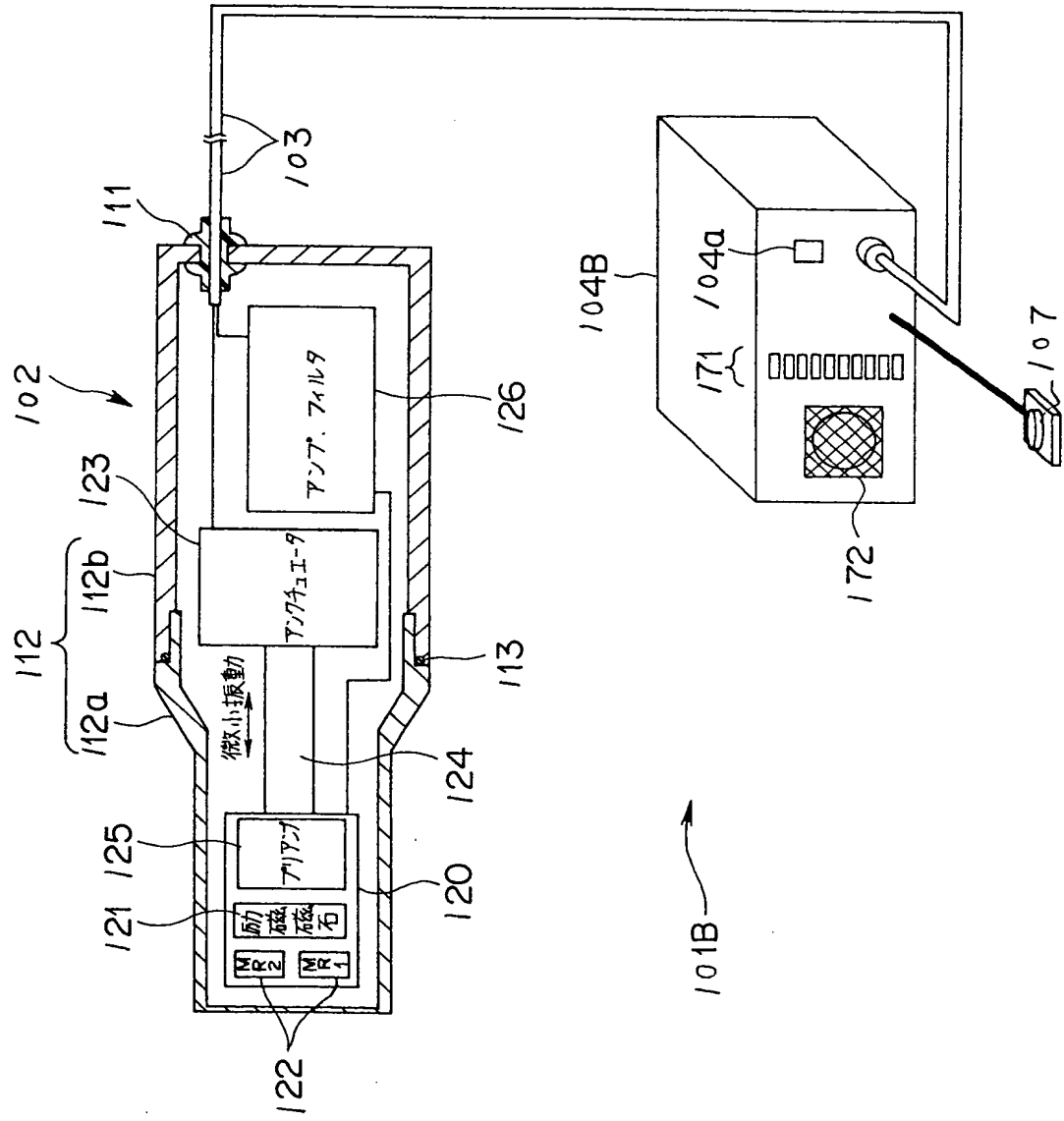


図36

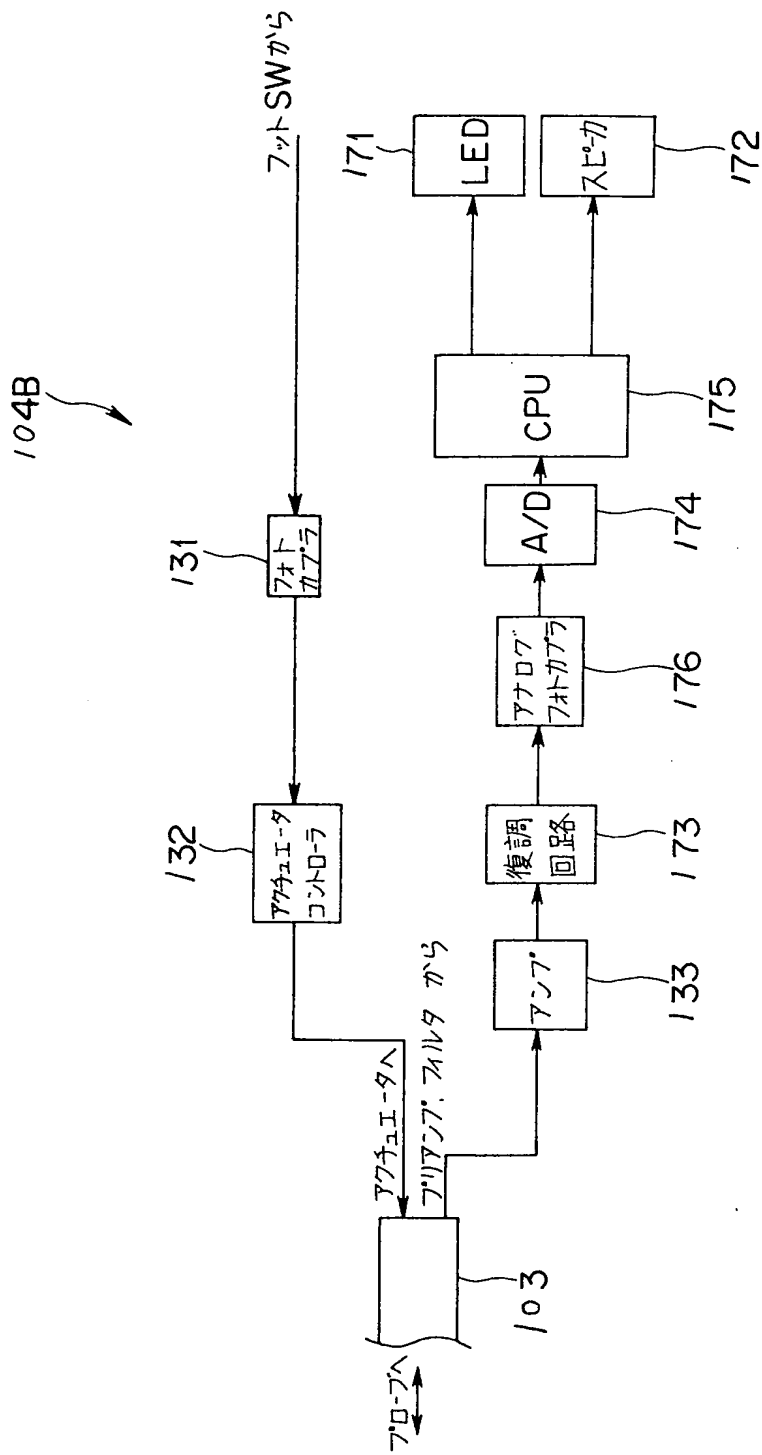




図37

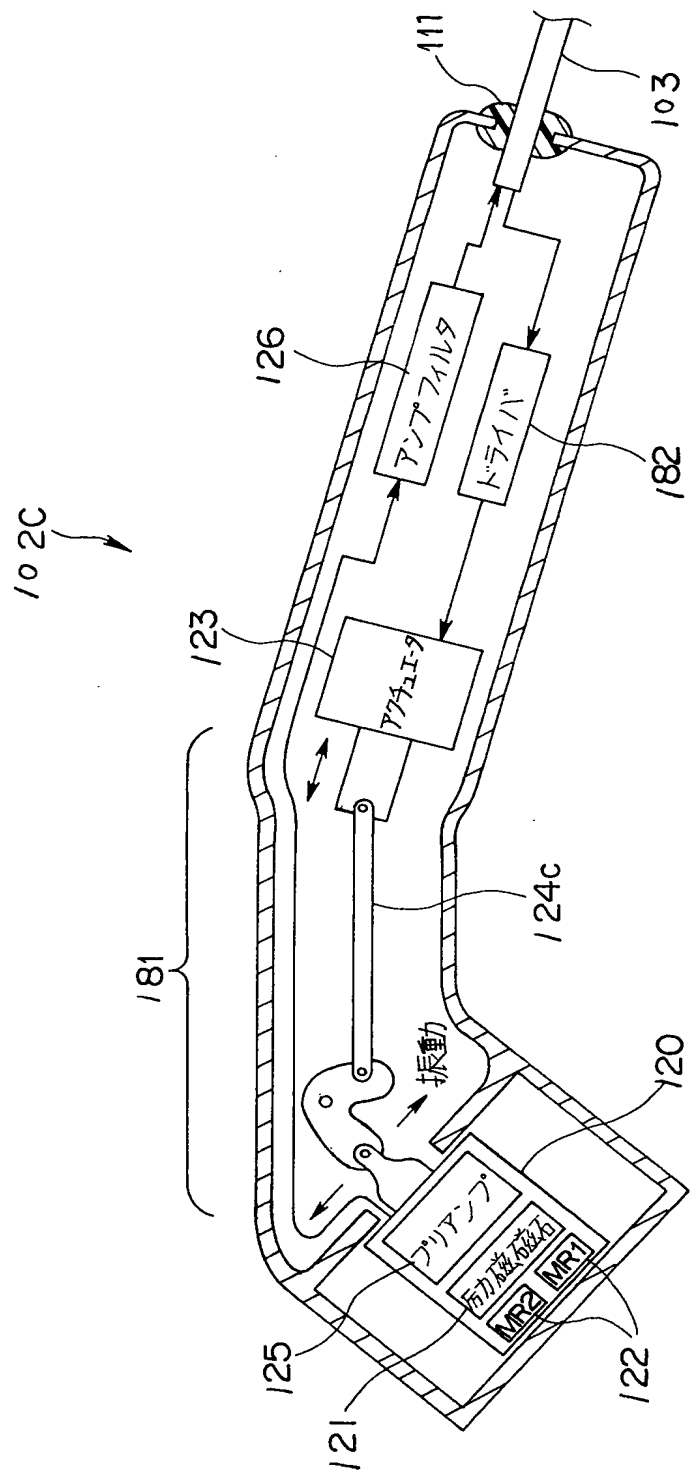


図38A

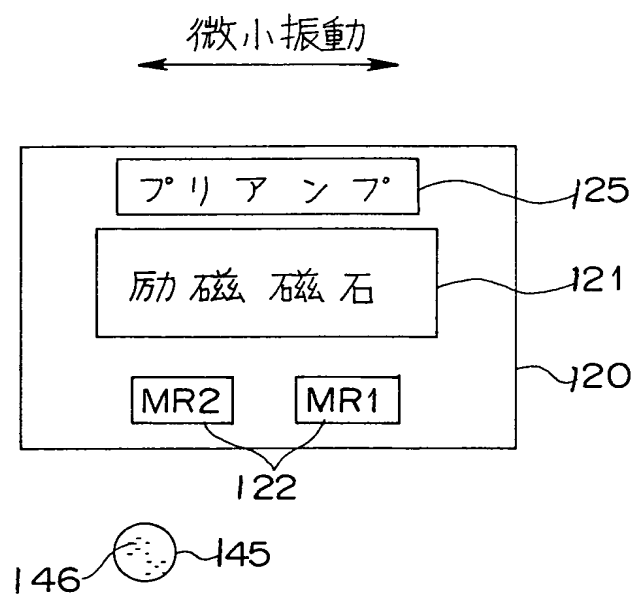


図38B

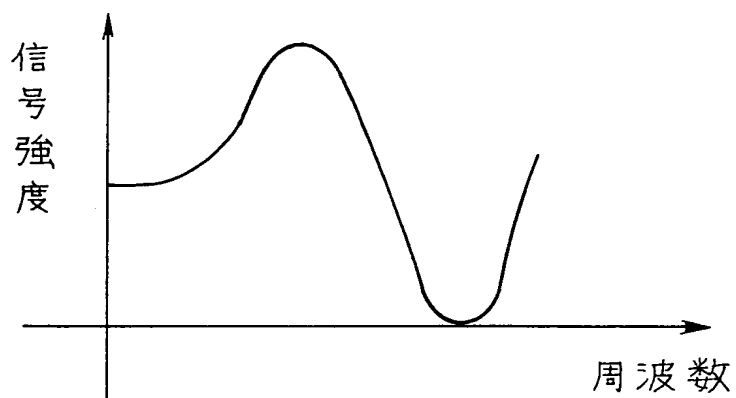


図39

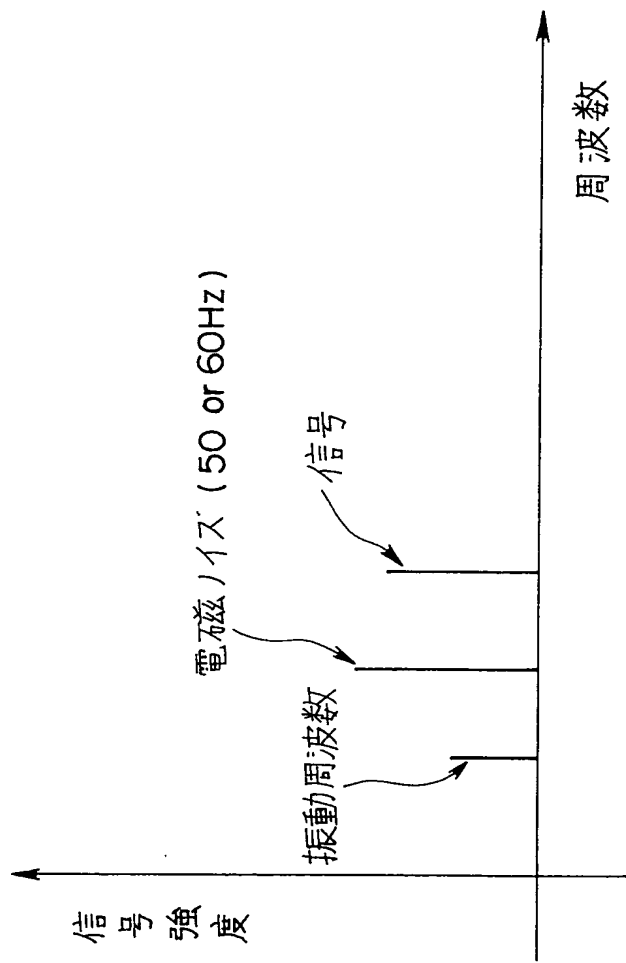


図40A

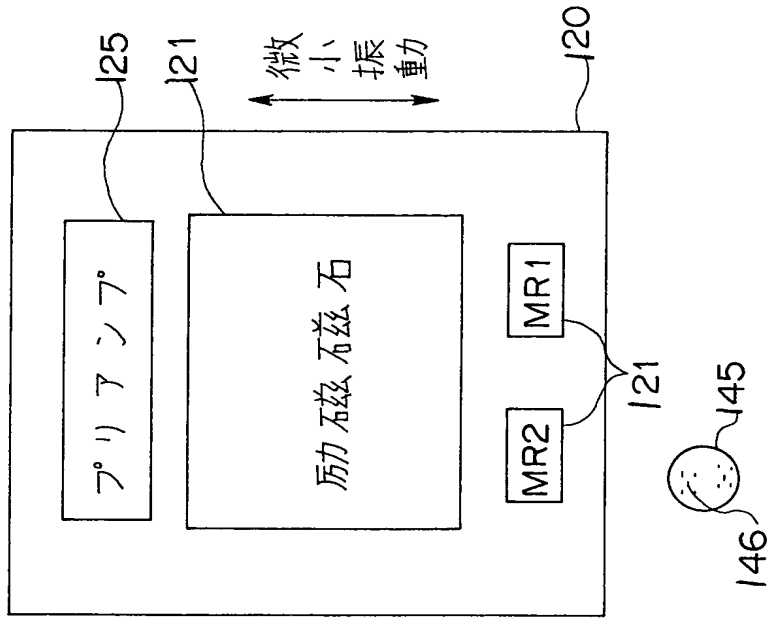


図40B

